Attorney Docket No.: A4944/T39900 AMAT No.: 004944/PDD/ELK/JW TTC No.: 016301-039900US

## PATENT APPLICATION

## Atmospheric Substrate Processing Apparatus For Depositing Multiple Layers on a Substrate

Inventor(s):

Michael Barnes P.O. Box 471182 San Ramon, CA 94583

Citizenship: U.S.

Michael S. Cox P.O. Box 259

Davenport, CA 95017 Citizenship: U.S.

Canfeng Lai 47615 Hoyt St. Fremont, CA 94539 Citizenship: P.R. China

John Parks

19 Torregata Loop San Jose, CA 95134 Citizenship: U.S.

Assignee:

APPLIED MATERIALS, INC.

P.O. Box 450A

Santa Clara, CA 95054

Entity:

Large